



AF  
Hw

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Applicant : Jingyi Bai et al.  
Serial No. : 10/618,220  
Filed : July 11, 2003  
Title : METHODS FOR FILLING HIGH ASPECT RATIO TRENCHES IN  
SEMICONDUCTOR LAYERS  
Docket No. : MIO 0109 PA  
Art Unit : 2825  
Examiner : Renzo Rocchegiani

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on November 12, 2004.

*Susan M. Juma*

Agent

Reg. No. 38,769

AMENDMENT AFTER FINAL REJECTION

This paper is being filed in response to the Office Action mailed September 21, 2004. Reconsideration and reexamination are respectfully requested in light of the amendments and remarks below, which are believed to place the application in condition for allowance or at least substantially reduce the issues for appeal.